

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of:	Yoshihide SENZAKI	Confirmation No.:	3254
Serial No.:	10/524,980	Art Unit:	2823
Filed:	March 22, 2006	Examiner:	Hsien Ming LEE
For:	<i>Low Temperature Deposition of Silicon Oxides and Oxynitrides</i>	Attorney Docket No:	067538-5172-US

PETITION FOR EXTENSION OF TIME UNDER 37 CFR § 1.136(a)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


Dear Commissioner:

It is respectfully requested that the time for response to the Final Office Action dated June 12 2008, be extended for a period of three-months from September 12, 2008, to December 12, 2008.

The fee for this extension is estimated to be \$1110.00. Please charge the required fee to Morgan, Lewis & Bockius LLP Deposit Account No. 50-0310 (order no. 067538-5172-US).

Respectfully submitted,

Date: December 12, 2008



Maria S. Swiatek, Esq. 37,244
Customer No.: 24341 (Reg. No.)
MORGAN, LEWIS & BOCKIUS LLP
2 Palo Alto Square
3000 El Camino Real, Suite 700
Palo Alto, California 94306
Ph. (650) 843-4000
Fax (650) 843-4001